

Title: Apparatus and Method to Achieve Continuous Interface  
and Ultrathin Film During Atomic Layer Deposition  
Inventor(s): Ofer Sneh, et al.  
Attorney Docket No.: 4551P002D

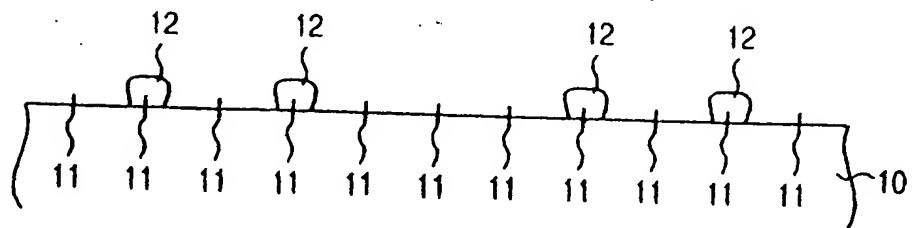


FIG. 1 (Prior Art)

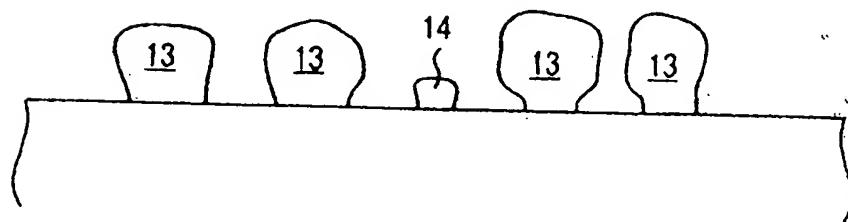


FIG. 2 (Prior Art)

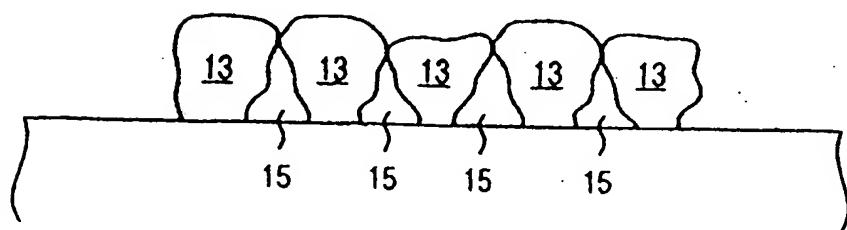


FIG. 3 (Prior Art)

Title: Apparatus and Method to Achieve Continuous Interface  
and Ultrathin Film During Atomic Layer Deposition  
Inventor(s): Ofer Sneh, et al.  
Attorney Docket No.: 4551P002D

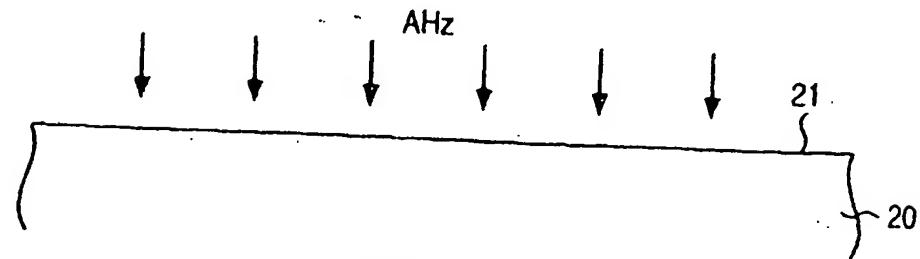


FIG. 4

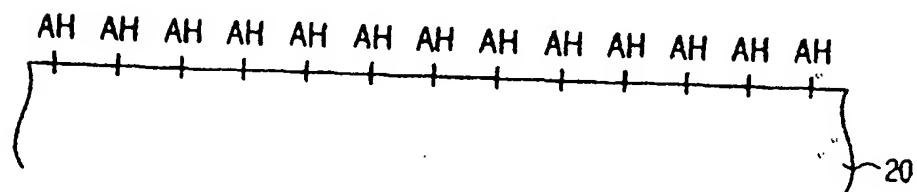


FIG. 5

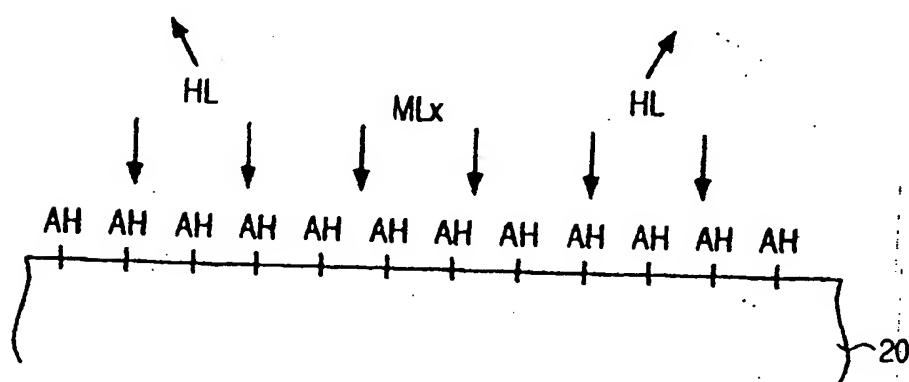


FIG. 6

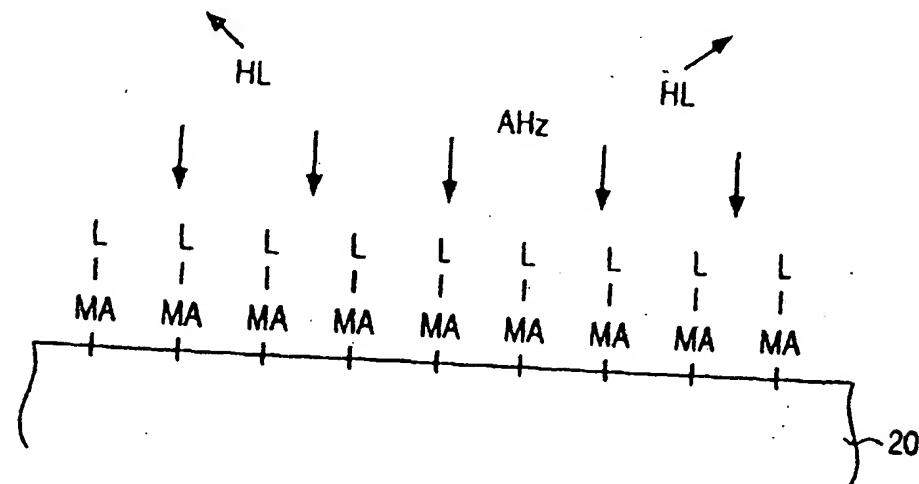


FIG. 7

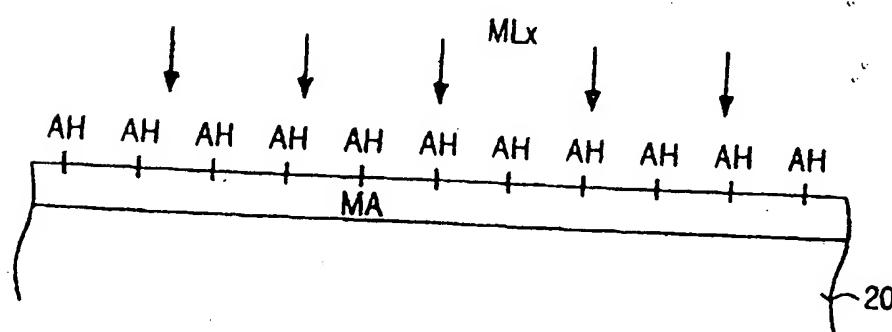


FIG. 8

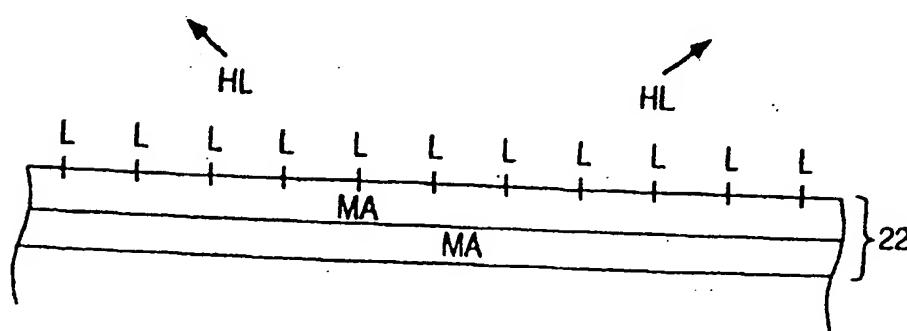


FIG. 9

Title: Apparatus and Method to Achieve Continuous Interface  
and Ultrathin Film During Atomic Layer Deposition  
Inventor(s): Ofer Sneh, et al.  
Attorney Docket No.: 4551P002D

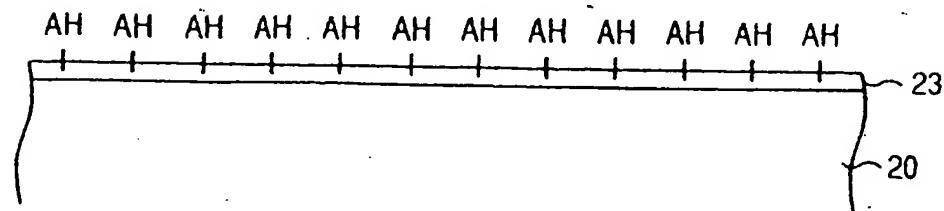


FIG. 10

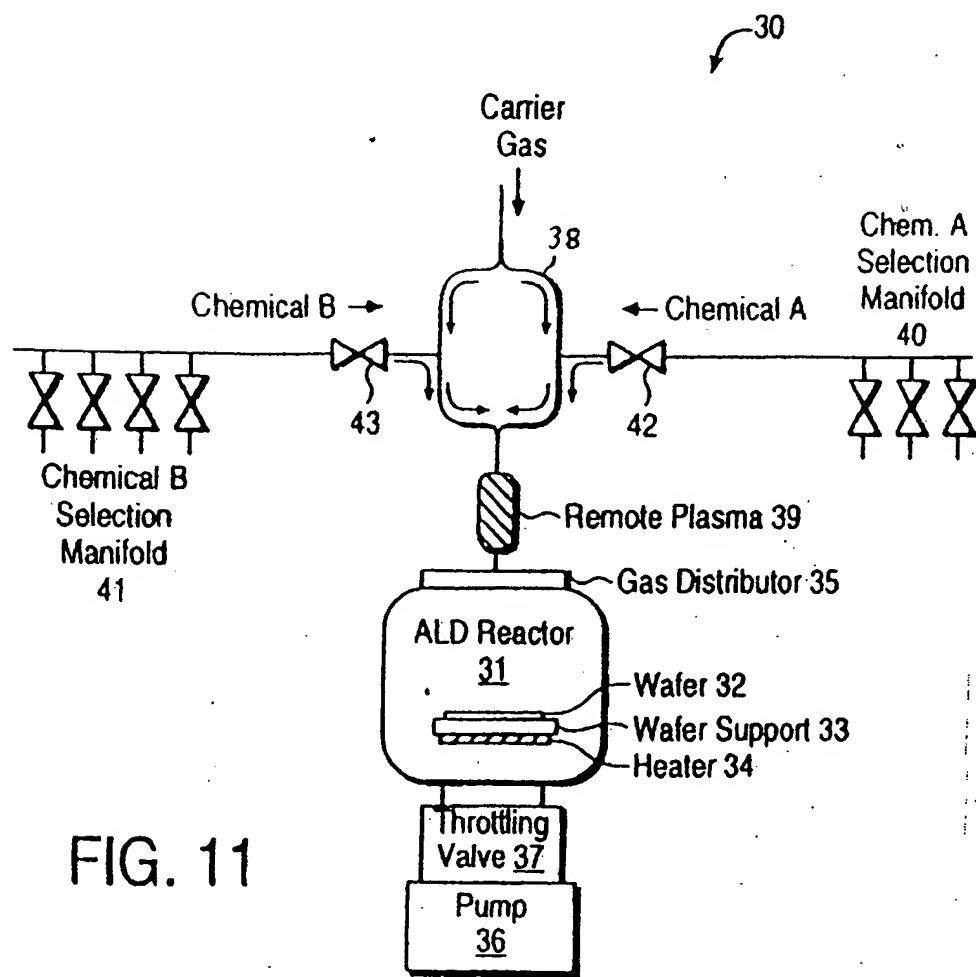


FIG. 11